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## Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application.

## Listing of Claims:

- 1. (Canceled)
- 2. (Currently Amended) The phase-shift-mask according to claim 9 elaim 1, wherein further comprising a third portion of the first pattern that is not transparent [[for]] to light.
- 3. (Currently Amended) The phase-shift-mask according to claim 9 elaim-1, wherein the first portions have a first width of the first portion extending in a first direction and a first length extending in a second direction that is orthogonal to the first direction, and the second portion has a second width of the second portion extending in [[a]] the first direction between adjacent first portions and a second length extending in the second direction between adjacent first portions, the ratio of the first width to the second width being different from [[1]] unity, and a first length of the first portion and a second length of the second portion extend in a second direction, the second direction being orthogonal to the first direction, the ratio of the first length to the second width length being different from [[1]] unity.
- 4. (Currently Amended) The phase-shift mask according to <u>claim 9</u> claim 1, wherein each of the <u>first</u> portions of the <u>first pattern is</u> are arranged symmetrically about at least one axis.
- 5. (Currently Amended) The phase-shift mask according to claim 2, wherein each of the first pattern is are arranged symmetrically about two orthogonal axes.
- 6. (Currently Amended) The phase-shift mask according to <u>claim 9 elaim 1</u>, wherein <u>each of</u> the first portions comprises a square, and the second portion comprises a set of four lines bordering and enclosing four sides of the square of <u>each of</u> the first portions.

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7. (Currently Amended) The phase-shift mask according to claim 9 elaim 1, wherein:

each of the first portions comprises a first sub-pattern being having a U-shape U-shaped;

the second portion comprises a plurality of second sub-patterns each having a U-shape
being U shaped;

open ends of the U-shapes of adjacent first and second sub-patterns are orientated towards each other[[,]];

each of the first portions comprises a third rectangular sub-pattern, which is enclosed on three sides by [[the]] an adjacent second sub-pattern of the second portion[[,]]; and

the second portion comprises a <u>plurality of</u> fourth rectangular sub-pattern, <u>each of</u> which is enclosed on three sides by [[the]] <u>an adjacent</u> first sub-pattern of the <del>second</del> <u>first</u> portion.

- 8. (Currently Amended) The phase-shift mask according to claim 9 elaim 1, wherein the first and second transmission transmittance are larger greater than 45 percent of the irradiated light.
  - 9. (New) A phase shift mask, comprising:

first portions arranged in a pattern across the phase shift mask, the first portions having a first area, a first transmittance of electric field strength of light to be irradiated through the phase shift mask, and a first phase shift characteristic with respect to light traversing the phase shift mask through the first portions; and

at least one second portion disposed adjacent the pattern of first portions across the phase shift mask, the second portion having a second area, a second transmittance of electric field strength of light to be irradiated through the phase shift mask, the second transmittance being different from the first transmittance, and a second phase shift characteristic with respect to light traversing the phase shift mask through the second portion;

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wherein the product of the first area and the first transmittance is substantially equal to the product of the second area and the second transmittance, such that a zero order diffraction of light is substantially absent from light irradiated through the phase shift mask.